



17x1/28/12

**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Attn: OIPE

Shigehiro NISHINO et al.

Group Art Unit: 2812

Application No.: 10/520,141

Docket No.: 122261

Filed: September 1, 2005

For: LARGE-DIAMETER SIC WAFER AND MANUFACTURING METHOD THEREOF

**SECOND REQUEST FOR CORRECTION OF PALM RECORDS**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

A Request for Correction of PALM Records was filed on January 24, 2006. A copy of the Request, a marked-up copy of the Official Filing Receipt and a date stamped receipt is attached hereto.

It is respectfully requested that the Corrected Filing Receipt be immediately forwarded to the attorneys of record at the address set forth below.

Respectfully submitted,

James A. Oliff  
Registration No. 27,075

Tarik M. Nabi  
Registration No. 55,478

JAO:TMN/sml

Date: July 24, 2006

OLIFF & BERRIDGE, PLC  
P.O. Box 19928  
Alexandria, Virginia 22320  
Telephone: (703) 836-6400

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Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Attached is a photocopy of the original filing receipt on which errors have been corrected in red. These errors are being brought to the attention of the Patent and Trademark Office so that it may correct its records.

Respectfully submitted,

James A. Oliff  
Registration No. 27,075

Linda M. Saltiel  
Registration No. 51,122

JAO:LMS/nxy

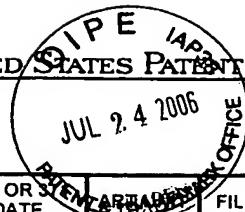
Date: January 24, 2006

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UNITED STATES PATENT AND TRADEMARK OFFICE



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APPL NO.	FILING OR SY (c) DATE	FIL FEE REC'D	ATTY.DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/520,141	09/01/2005	2812	1030	122261	3	5

25944  
OLIFF & BERRIDGE, PLC  
P.O. BOX 19928  
ALEXANDRIA, VA 22320

CONFIRMATION NO. 9522

FILING RECEIPT



\*OC000000017852555\*

Date Mailed: 01/18/2006

Receipt is acknowledged of this regular Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please mail to the Commissioner for Patents P.O. Box 1450 Alexandria Va 22313-1450. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

**Applicant(s)**

Shigehiro Nishino, Kyoto, JAPAN; Kyoto-shi  
Kazutoshi Murata, Okayama, JAPAN; Tamano-shi

**Assignment For Published Patent Application**

IMITSU ENGINEERING & SHIPBUILDING CO., LTD, TOKYO, JAPAN

**Power of Attorney:** The patent practitioners associated with Customer Number 25944.

**Domestic Priority data as claimed by applicant**

This application is a 371 of PCT/JP03/08312 06/30/2003

**Foreign Applications**

JAPAN 2002-202953 07/11/2002

**Projected Publication Date:** 04/27/2006

**Non-Publication Request:** No

**Early Publication Request:** No

**Title**

\* PLEASE SEE PAGE 2 FOR CORRECTIONS TO THE TITLE \*

~~Large-diameter-sic wafer and manufacturing method thereof~~  
~~Large-Diameter SiC wafer and Manufacturing Method Thereof~~

Preliminary Class

438

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Since the rights granted by a U.S. patent extend only throughout the territory of the United States and have no effect in a foreign country, an inventor who wishes patent protection in another country must apply for a patent in a specific country or in regional patent offices. Applicants may wish to consider the filing of an international application under the Patent Cooperation Treaty (PCT). An international (PCT) application generally has the same effect as a regular national patent application in each PCT-member country. The PCT process **simplifies** the filing of patent applications on the same invention in member countries, but **does not result** in a grant of "an international patent" and does not eliminate the need of applicants to file additional documents and fees in countries where patent protection is desired.

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**Title 37, Code of Federal Regulations, 5.11 & 5.15**

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**PTO RECEIPT FOR FILING OF PAPERS**

► Mail Room (Regular Delivery)

The following papers have been filed:

Req. Corr. PALM; marked-up Filing Receipt.



**Name of Applicant:** Shigehiro NISHINO et al.

**Serial No.:** 10/520,141

**Atty. File No.:** 122261

**Title (New Cases):**

**Sender's Initials:** JAO/nxy

a a /  
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**PATENT OFFICE DATE STAMP**



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